

80/578752

APPROVED FOR PCT/PTO 04 MAY 2006

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of: Phillips, et al.

Attorney Docket No.: NIKOP064/PA0647

Application No.: To Be Assigned

Examiner: To Be Assigned

Filed: May 4, 2006

Group: To Be Assigned

Title: THERMOPHORETIC TECHNIQUES  
FOR PROTECTING RETICLES FROM  
CONTAMINANTS

**CERTIFICATE OF EXPRESS MAILING**

I hereby certify that this paper and the documents and/or fees referred to as attached therein are being deposited with the United States Postal Service on May 4, 2006 in an envelope as "Express Mail Post Office to Addressee" service under 37 CFR §1.10, Mailing Label Number EV860995125US, addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Max Adams

**INFORMATION DISCLOSURE STATEMENT  
37 CFR §§1.56 AND 1.97(b)**

Commissioner for Patents  
Alexandria, VA 22313-1450

Dear Sir:

The references listed in the attached PTO Form 1449 may be material to examination of the above-identified patent application. Applicants submit these references in compliance with their duty of disclosure pursuant to 37 CFR §§1.56 and 1.97. The Examiner is requested to make these references of official record in this application.

This Information Disclosure Statement is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that these references indeed constitute prior art.

This Information Disclosure Statement is filed within three (3) months of the filing date of the above-referenced application. Accordingly, it is believed that no fees are due in connection with the filing of this Information Disclosure Statement. However, if it is determined that any fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 500388 (Order No. NIKOP064).

Respectfully submitted,

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<b>Form 1449 (Modified)</b>  <b>Information Disclosure Statement By Applicant</b>  (Use Several Sheets if Necessary)	Atty Docket No. <b>NIKOP064/PA0647</b>	<b>10/578752</b> Application No. <b>To Be Assigned</b>
	Applicant: <b>Alton, et al.</b> Filing Date <b>May 4, 2006</b>	Group <b>To Be Assigned</b>

**U.S. Patent Documents**

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
	1A	6,090,176	07/18/00	Yoshitake, et al.			03/11/98
	1B	6,239,863	05/29/01	Catey, et al.			12/29/99
	1C	6,281,510	08/28/01	Yoshitake, et al.			05/02/00
	1D	6,317,479	11/13/01	Chiba, et al.			05/16/97
	1E	6,646,720	11/11/03	Ramamoorthly, et al.			09/21/01
	1F	6,728,332	04/27/04	Chiba, et al.			10/05/01
	1G	6,753,945	06/22/04	Heerens, et al.			02/27/03
	1H	6,906,783	06/14/05	del Puerto, et al.			02/20/03
	1I	6,826,451	11/30/04	del Puerto, et al.			08/22/02
	1J	6,912,043	06/28/05	Galburt			10/27/03

**Foreign Patent or Published Foreign Patent Application**

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	1K	1491960A2	29/12/04	EP			X	
	1L	1120690A2	01/08/01	EP			X	

**Other Documents**

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	1M	Rader, Daniel J., et al., <i>Verification studies of thermophoretic protection for EUV masks</i> , Emerging Lithographic Technologies VI, Proceedings of SPIE Vol. 4688 (2002), pp. 182-193.
Examiner		Date Considered

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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	Applicant: <b>Alton, et al.</b> Filing Date <b>May 4, 2006</b>	Group <b>To Be Assigned</b>

**U.S. Patent Documents**

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
	2A	6,253,464	07/03/01	Klebanoff, et al.			08/18/00
	2B	6,153,044	11/28/00	Klebanoff, et al.			04/30/98
	2C	6,414,744	07/02/02	Kuiper, et al.			04/19/00
	2D	2002/0096647	07/25/02	Moors, et al.			10/09/01
	2E	6,492,067	12/10/02	Klebanoff, et al.			12/03/99
	2F	6,153,044	11/28/00	Klebanoff, et al.			04/30/98
	2G	5,061,444	10/29/91	Nazaroff, et al.			03/22/91
	2H	5,169,272	12/08/92	Bonora, et al.			11/01/90
	2I	2003/0082030	05/01/03	del Puerto, et al.			08/12/02

**Foreign Patent or Published Foreign Patent Application**

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No

**Other Documents**

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
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